

Japan TC Chapter of Automation Technology Global Technical Committee Meeting Summary and Minutes

Japan Standards Fall 2014 Meetings
Thursday, September 25, 2014, 1:30 p.m. – 5:00 p.m.
SEMI Japan office, Tokyo, Japan

Next Committee Meeting

Tuesday, December 9, 2014, 1:30 p.m. – 5:00 p.m. <Japan Standard Time>
Japan Standards Winter 2014 Meetings, Tokyo

Committee Announcements (optional)

None

Table 1 Meeting Attendees

Italics indicates virtual participants

Co-Chairs: Makoto Ishikawa (Nisshinbo Mechatronics), Ken Sambu (Mitsubishi Electric), Terry Asakawa (Tokyo Electron)

SEMI Staff: Chie Yanagisawa (SEMI Japan)

Attendee: 6 + **SEMI:** 1

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
Daihen	Otogawa	Yasunobu	Tokyo Electron	Asakawa	Terry
Mitsubishi Electric	Sambu	Ken	Tokyo Electron	Murata	Naoko
Nisshinbo Mechatronics	Ishikawa	Makoto			
Siemens	Ohbuchi	Fumiyasu	SEMI Japan	Yanagisawa	Chie

** alphabetical order by company name*

Table 2 Leadership Changes

None

Table 3 Ballot Results (or move to Section 4, Ballot Review)

Passed ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

Failed ballots and line items were returned to the originating task forces for re-work and re-balloting.

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
5697A	Line Item Revisions to SEMI PV35-0414, Specification for Horizontal Communication between Equipment for Photovoltaic Fabrication System	
Line Item 1	Byte order on communication line is not specified precisely but recommended as endian, and it causes mismatch between different equipment suppliers. This Standard shall specify valuable data and define how to align data, but shall not define byte order. Byte order shall be defined by PV35.1. Accordingly, delete section 7.3.5.	Passed as balloted
5698A	Line Item Revision to SEMI PV35.1-0114, Media Interface Specifications for A Horizontal Communication between Equipment	
Line Item 1	The definition how to connect and maintain sessions of TCP are not specified. Revise the following items accordingly.	Passed as balloted

Table 4 Authorized Ballots (or move to Section 7, New Business)

None

Table 5 Authorized Activities (or move to Section 7, New Business)

None

Table 6 New Action Items (or move to Section 8, Action Item Review)

None

Table 7 Previous Meeting Actions Items (or move to Section 8, Action item Review)

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
20140729-1:	Staff:	To forward the TFOF for Global EIS Task Force modified during meeting to relevant members and responsible staff for their review, then forward to GCS for their approval. => CLOSE
20140729-2:	Japan members of Global EIS TF :	To review the SNARF # 5222 => OPEN
20140729-3:	Staff:	To forward the SNARF #5697 and #5698 to Global EIS Task Force leaders for their review and then, forward to GCS for their approval. => CLOSE

1 Welcome, Reminders, and Introductions

Makoto Ishikawa (Nisshinbo Mechatronics) called the meeting to order at 1:30 p.m. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

2 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting.

Motion:	To approve the previous meeting minutes written as it is.
By / 2nd:	Ken Sambu (Mitsubishi Electric) / Naoko Murata (Tokyo Electron)
Discussion:	None
Vote:	4 in favor and 0 opposed. Motion Passed.

3 Liaison Reports

3.1 *Europe TC Chapter*

There is no report.

3.2 *SEMI Staff Report*

Chie Yanagisawa (SEMI Japan) gave the SEMI Staff Report. Of note:

- PV Automation TC Transformation to Automation Technology TC
- Guidance for Task Force Meeting Management
- SEMICON Japan 2014 to be held at Tokyo Big Sight from December 3 to December 5.

Attachment: [01_SEMI Staff Report 2014 September_R0.3](#) and [02_Guidance for Task Force Meeting Management \(TF Leaders\)](#)

4 Ballot Review

4.1 Document #5697A: Line Item Revision to SEMI PV35-0414, “Specification for Horizontal Communication between Equipment for Photovoltaic Fabrication System”

4.1.1 Line Item #1: Byte order on communication line is not specified precisely but recommended as endian, and it causes mismatch between different equipment suppliers. This Standard shall specify valuable data and define how to align data, but shall not define byte order. Byte order shall be defined by PV35.1. Accordingly, delete section 7.3.5.

This Line item passed committee review as balloted. The details are described in the attached #5697A Procedural Review Voting Sheet.

Attachment: [03_5697A_ProceduralReview_Final](#)

4.2 Document 5698A: Line Item Revision to SEMI PV35.1-0114, “Media Interface Specifications for a Horizontal Communication between Equipment”

4.2.1 Line Item #1: The definition how to connect and maintain sessions of TCP are not specified. Revise the following items accordingly.

This Line item passed committee review as balloted. The details are described in the attached #5698A Procedural Review Voting Sheet.

Attachment: [04_5698A_ProceduralReview_Final](#)

5 Subcommittee & Task Force Reports

5.1 Equipment Interface Specification (EIS) Task Force

Makoto Ishikawa (Nisshinbo Mechatronics) reported for the Equipment Interface Specification (EIS) Task Force. Of note:

- The Revised TFOF and Revised SNARFs were approved by GCS on September 24, 2014
 - TFOF for Global Equipment Interface Specification (EIS) TF
 - #5697 SNARF for Line Item Revisions to SEMI PV35-0114, “Specification for Horizontal Communication between Equipment for Photovoltaic Fabrication System”
 - #5698 SNARF for Line Item Revisions to SEMI PV35.1-0114, “Media Interface Specifications for a Horizontal Communication between Equipment”

6 Old Business

None

7 New Business

7.1 Future activity

Terry Asakawa (Tokyo Electron) addressed the committee on this topic. He stated that to supply in package would be very significant in order that Standards of this area to be widely used, which is quite different from standardization of semiconductor industry. Therefore, it will have been very important for this activity to have liaison with FlowMasterForum.

He also continued that the activity of FlowMasterForum has been in a slowdown with the stagnation of PV industry. Now, PV Automation Committee has been transformed to Automation Technology Committee, so that Automation Technology Committee could have a strong relationship with FlowMasterForum

8 Action Item Review

8.1 Open Action Items

Chie Yanagisawa (SEMI Japan) reviewed the open action item. This can be found in the Open Action Items table at the beginning of these minutes.

8.2 New Action Items

None

9 Next Meeting and Adjournment

The next meeting of the Japan TC Chapter of Automation Technology Global Technical Committee is scheduled for 1:30 p.m. – 5:00 p.m., Tuesday, December 9 at Japan Standards Winter 2014 Meetings at SEMI Japan office in Tokyo.

Respectfully submitted by:
Chie Yanagisawa
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SEMI Japan
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Minutes approved by:

Makoto Ishikawa (Nisshinbo Mechatronics), Co-chair	September 25, 2014
Ken Sambu (Mitsubishi Electric) , Co-chair	September 25, 2014
Terry Asakawa (Tokyo Electron), Co-chair	September 25, 2014

Table 8 Index of Available Attachments #1

#	<i>Title</i>	#	<i>Title</i>
01	SEMI Staff Report 2014 September_R0.3 and	03	5697A_ProceduralReview_Final
02	Guidance for Task Force Meeting Management (TF Leaders)	04	5698A_ProceduralReview_Final

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.